



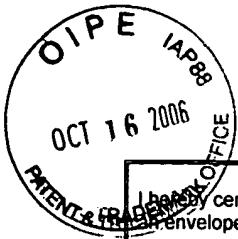
DFW

AMENDMENT TRANSMITTAL LETTER				Docket No. FIS920030360US1 Conf #3405
Application No. 10/709,406	Filing Date 05/03/2004	Examiner Thanh T. Nguyen	Art Unit 2813	
Applicant(s): Colin J. Brodsky et al.				
Invention: METHOD TO REDUCE PHOTORESIST PATTERN COLLAPSE BY CONTROLLED SURFACE MICROROUGHENING				
TO THE COMMISSIONER FOR PATENTS				
Transmitted herewith is an amendment in the above-identified application.				
The fee has been calculated and is transmitted as shown below.				
CLAIMS AS AMENDED				
Total Claims	Claims Remaining After Amendment 14	Highest Number Previously Paid 20	Number Extra Claims Present 0	Rate
Independent Claims	2	- 3	0	
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>				
Other fee (please specify):				
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:				
<input checked="" type="checkbox"/> Large Entity <input type="checkbox"/> Small Entity <input type="checkbox"/> No additional fee is required for this amendment. <input type="checkbox"/> Please charge Deposit Account No. _____ in the amount of \$ _____. A duplicate copy of this sheet is enclosed. <input type="checkbox"/> A check in the amount of \$ _____ to cover the filing fee is enclosed. <input type="checkbox"/> Payment by credit card. Form PTO-2038 is attached. <input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. 09-0458 as described below. A duplicate copy of this sheet is enclosed. <input checked="" type="checkbox"/> Credit any overpayment. <input checked="" type="checkbox"/> Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.				
Dated: October 11, 2006				
Daryl K. Neff Attorney Reg. No.: 38,253				

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, in an envelope addressed to: MS Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.

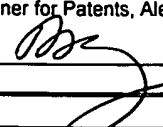
Dated: October 11, 2006

Signature:  (Daryl K. Neff)



I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: MS Amendment, Commissioner for Patents, Alexandria, VA 22313-1450.

Dated: October 11, 2006

Signature 
(Daryl K. Neff)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Colin J. Brodsky et al.	Date: October 11, 2006
Serial Number: 10/709,406	Examiner: Thanh T. Nguyen
Filed: May 3, 2004	Group Art Unit: 2813 Conf. #3405
Title: METHOD TO REDUCE PHOTORESIST PATTERN COLLAPSE BY CONTROLLED SURFACE MICROROUGHENING	Todd M.C. Li IBM Corporation D/18G, B/321, Zip 482 2070 Route 52 Hopewell Junction, NY 12533

AMENDMENT

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated October 11, 2006, applicants submit the following amendments and remarks for the Examiner's consideration.

FIS920030360US1